# Atomic Oxygen Maximization in High-Voltage Pulsed Cold Atmospheric Plasma Jets

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Abstract—This paper presents a new device generating highvoltage pulsed cold atmospheric plasma jets. With these plasmas, the quantity of atomic oxygen (and, accordingly, the chemical activity) is a lot higher than that in previous researches. The main characteristic of the new device is the usage of three tubular needle-type electrodes connected in parallel. By applying highvoltage pulses (with 20-30-kV amplitude, duration of hundreds of nanoseconds, and hundreds of pulses per second), three independent discharges are formed in the discharge room. The plasma-forming gas is He, with a low quantity of oxygen introduced through the high-voltage electrodes. Each discharge has an optimal percentage of 0.5% vol. O<sub>2</sub> in He, which maximizes the quantity of atomic oxygen in the plasma. The plasmas of the three discharges unite to a single jet though, which contains a quantity of atomic oxygen that is a lot higher than that of the plasma of each discharge. The emission spectra of the plasma jets show the maximization of the intensity of the O I 777 nm line when a concentration of 1.5% vol.  $O_2$  in He (three times higher than so far) is introduced in the plasma-forming gas.

*Index Terms*—Atomic oxygen, cold atmospheric plasma jets, pulsed high voltage.

## I. INTRODUCTION

**A** TMOSPHERIC pressure cold plasmas are still intensively studied for applications such as modifying the properties of certain surfaces [1]–[3], physical and chemical modifications of polymers [4], thin-film deposition [5]–[7], nanotechnologies [8], and depollution of gaseous or liquid environments [9], [10]. However, the largest part of applications of these plasmas belongs to the biomedical field: microorganism destruction (decontamination of biological, food-related, etc., media) [11]–[14], *in vitro* and *in vivo* cell treatment [15]–[20], and various medical treatment tests [21]–[25]. All these applications belong to one of the newest research fields of the last few years: plasma medicine [26], [27]. This paper regards plasma medicine as well: We aim to increase the efficiency of the atmospheric cold plasma jets treatment of microorganisms and of normal and tumoral cells.

There are different types of atmospheric pressure cold plasma sources, depending on the voltage applied between the

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electrodes of the device employed: microwave voltage, radiofrequency voltage, ac voltage (tens of kilohertz), and high pulsed voltage. An inert gas (He or Ar) is the main plasmaforming gas. For biomedical applications, it is, however, necessary for the plasma to be chemically activated. That is why minute amounts of an additional gas as the source of reactive species are used. In most cases, reactive plasma is generated as a jet, which allows for the rapid transport of the excited species on the treated object.

In this paper, just like in our previous ones [28]–[30], the interelectrode voltage applied for obtaining the plasma is pulsed high voltage, with amplitudes of 20–30 kV, 100–500-ns width at half maximum, and frequencies of tens of hundreds of pulses per second (pps).

Molecular oxygen is used as the source of reactive species in our research.

The chemical processes start with a generation of atomic oxygen, produced by electron impact dissociation [31], by dissociative attachment [31], and by Penning ionization [32].

Little is known about the way in which atomic oxygen acts on bacteria and animal cells. It was suggested [33] that atomic oxygen may be responsible for the oxidation of proteins. The efficiency of the atomic oxygen in destroying species with high clinical significance has been shown for *Escherichia coli*, *Pseudomonas aeruginosa*, and *Bacillus cereus* [34]. The atomic oxygen plays an important role in the inactivation of many other bacterial strains, proving its applicability in the sterilization of culture media, material surfaces, and air [26], [33], [35], [36]. This makes it ideal for cleaning surgical implants, which are often contaminated with fragments of bacteria cells even after sterilization.

Nevertheless, by the reactive oxygen species that it produces, the atomic oxygen is indirectly involved in the destruction of pathogens and induction of apoptosis or necrosis in mammalian cells, including cancer ones [26], [35].

In order to obtain higher quantities of atomic oxygen, it is necessary to increase the concentration of molecular oxygen  $(O_2)$  in plasma-forming gas (He, in our case). Unfortunately, this increase brings along the decrease of the plasma current. Consequently, the quantity of atomic oxygen produced within the plasma has an initial increase along with the concentration of molecular oxygen, and then, it drops as a result of the decrease of the plasma jet current. Therefore, there is an optimal concentration of  $O_2$  in He/Ar that maximizes the quantity of atomic oxygen.

For the RF voltage supply of the plasma jet, experimental works [37] have determined an optimal concentration of 0.5%-0.6% vol. O<sub>2</sub>/He. Using a model that considers



Fig. 1. High-voltage pulsed cold atmospheric plasma jet generator (the initial transparent device).

35 dominant chemical reactions in the RF He/O<sub>2</sub> plasma, an optimal theoretical value of 0.5% vol. O<sub>2</sub>/He [38] has been obtained. Regarding the submicrosecond pulsed atmospheric plasma (our case), the value considered as optimal for the oxygen concentration is 0.5% vol. O<sub>2</sub>/He [39] as well.

In all the papers mentioned earlier, a coaxial device with high-voltage central electrode was used for generating the plasma jet. The ground electrode was mounted on the exterior, separated from the central electrode by a dielectric barrier.

In the following paper parts, we will describe a new pulsed cold atmospheric plasma jet-generating device, which allows for the increase of the optimal concentration of molecular oxygen in He and, consequently, for the increase of the quantity of atomic oxygen in the plasma jet. The experimental results will be presented and commented as well.

#### **II. EXPERIMENTAL SYSTEM**

The key component of the experimental system is the high-voltage pulsed cold atmospheric plasma jet generator (Fig. 1). A dielectric piston is placed inside a cylinder (inner diameter = 20 mm), which is also a dielectric. The piston is penetrated by three medical syringe needles. On the surface of the piston, the exit orifices of the needles are evenly placed, on a circle with a radius of 8.5 mm. The part of the needle coming out of the piston is 1.5 mm long. The opposite ends of the needles are electrically connected in parallel. In addition, oxygen is introduced through the needles, as a chemical activation gas. The inert gas (He) is introduced through the center of the piston. The syringe needles behave as high-voltage electrodes. The ground electrode is the opaque copper part, mounted at the end of the dielectric cylinder, around the exit nozzle. Electrical discharges are produced in the mixture of  $He/O_2$  (the oxygen concentration being of a few percentages only) by applying high-voltage pulses in the shape shown in Fig. 2 between the syringe needles and the ground electrode. The space distribution of the syringe needles allows for three independent electrical discharges to be produced inside the discharge room (Fig. 1). The plasma of the three electrical discharges is pushed toward the gas flow through the exit orifice, taking the shape of a unique plasma jet.



Fig. 2. Voltage applied between the high-voltage electrodes (syringe needles) and the ground electrode.



Fig. 3. Final device, generating high-voltage pulsed cold atmospheric plasma jet.

The final variant of the device (Fig. 3) is made of Teflon, for increasing the reliability when working with high-voltage pulses. In this case, the ground electrode surrounds the Teflon cylinder at 1-cm distance from its end.

For the cell treatment, the cells are immersed in culture media. To simulate this type of experiments, the plasma jet falls down on the surface of a tap water (Fig. 3). This water has an electrical conductivity of 800–1000  $\mu$ S · cm<sup>-1</sup>, in the range of electrical conductivities of cell culture media. The tap water container, with a diameter of 55 mm, is placed on a copper plate electrically connected to the ground.

The voltage/current pulses are measured with Tektronix P6015A and P6012 probes, respectively. The probes are coupled to the Tektronix TDS 2024B oscilloscope.

The gas flow rates have been measured by using flow controllers: 1) Cole Parmer type with a range of 0–5 L/min (for He) and 2) Aalborg GFC-17 type with a range of 0–50 mL/min (for  $O_2$ ).

The emission spectra of the plasma jets were obtained using an Ocean Optics HR4000 spectrometer. Its optical resolution is 0.75 nm full width at half maximum. The spectra are displayed



Fig. 4. Arrangement which allows that the spectrometer observation axis be collinear with the plasma jet (axial view).

on the computer screen, using SpectraSuite. The spectrometer allows for the adjustment of the integration times so that the saturation problems should all be solved.

For result confidence, the plasma emission spectra have been noticed on two directions.

- 1) The observation axis is perpendicular to the plasma jet (side view). The lens of the spectrometer aimed at an area that was 2 mm away from the exit orifice of the jet.
- 2) The observation axis is collinear with the plasma jet (axial view). In this case (Fig. 4), the plasma jet hits a glass plate on the side where a thin (200-nm) layer of indium tin oxide (ITO) was deposited by magnetron sputtering. This layer is optically transparent and has a good electrical conductivity. A metal wire makes the electrical contact between the layer and the water in the dielectric container. The lens and the optical fiber making the connection with the HR4000 spectrometer "look" from the other side of the glass plate, along the axis of the plasma jet.

### **III. EXPERIMENTAL RESULTS AND DISCUSSIONS**

During our previous research, plasma jets have been generated using cylindrical devices, with a unique high-voltage electrode axially placed in the device [30]. In these conditions, we have experimentally demonstrated that the optimal concentration of  $O_2$  in He that maximizes the production of atomic oxygen was of 0.5%, congruent with the results of other authors [37]–[39].

In this paper, in order to determine the optimal working voltage, we initially monitored the evolution of the O I 777 nm line (the unresolved triplet O I 777.194, O I 777.417, and O I 777.539 nm) intensity depending on the amplitude of the interelectrode high-voltage pulses. This spectral line corresponds to  $3^{5}P - 3^{5}S^{0}$  atomic oxygen transition, according to the U.S. National Institute of Standards and Technology database. Fig. 5 shows the dependence of the O I 777 nm line intensity of the interelectrode voltage amplitude, for two O<sub>2</sub> admixtures of 1% and 1.5% in the discharge. The O I 777 nm line intensity is rising linearly with discharge voltage. The increase in this line



Fig. 5. Dependence of the O I 777 nm line intensity of the interelectrode voltage amplitude, for two  $O_2$  admixtures in He: 1% and 1.5%. He flow rate: 2.5 L/min. Pulse repetition frequency: 100 pps. Spectrometer integration time: 600 ms. Side view.



Fig. 6. Plasma jet currents at several  $O_2$  concentrations, for the same interelectrode voltage pulse. From the most intense to the weakest current, the  $O_2$ concentrations are 0%, 0.5%, 1%, 1.5%, and 2%, respectively. He flow rate: 2.5 L/min.

intensity could be explained by assuming an increasing electron energy with the input voltage, which increases the number of  $O_2$  dissociations. Under these circumstances, the subsequent experiments were performed with 25-kV voltage amplitudes.

Fig. 6 shows the current pulses at several concentrations of  $O_2$  in He, for the same interelectrode voltage pulse. We notice the constant decrease of the plasma jet current together with the increase of the concentration of molecular oxygen. The quantity of atomic oxygen, highlighted by the O I 777 nm line, shows, however, a different evolution.

Fig. 7 shows plasma jet emission spectra for several concentrations of oxygen in He. The observation axis is perpendicular to the plasma jet (side view). The He flow rate is 2.5 L/min. The voltage pulses between the electrodes have the shape shown in Fig. 2 and are repeated with a frequency of 100 pps. All emission spectra reveal the presence of excited He and atomic oxygen in the plasma jet, as well as some excited N<sub>2</sub> molecules (from the air entrained in the plasma jet). The He (587 and 706 nm) and N<sub>2</sub> (337–406 nm) lines have maximum amplitudes at zero concentration of O<sub>2</sub> in He (Fig. 8). The addition of O<sub>2</sub> to the plasma-forming gas led to significant decreases of the He and N<sub>2</sub> lines, but without affecting the atomic oxygen emission



Fig. 7. Plasma jet emission spectra for several concentrations of oxygen in He: (a) 0.5%, (b) 1%, (c) 1.5%, and (d) 2%. The observation axis is perpendicular to the plasma jet (side view). He flow rate: 2.5 L/min. High-voltage amplitude: 25 kV. Pulse repetition frequency: 100 pps. Spectrometer integration time: 600 ms.



Fig. 8. Main spectral lines of the emission spectra of the plasma jets, with He only as the working gas. He flow rate: 2.5 L/min. High-voltage amplitude: 25 kV. Pulse repetition frequency: 100 pps. Spectrometer integration time: 600 ms. Side view.

at 777 nm (Fig. 7). This means that a significant fraction of the plasma electrons is used to produce O-containing species from the  $O_2$  molecules, leaving fewer electrons to collide and excite the He atoms and the  $N_2$  molecules.

In Fig. 9, we can notice the decrease of intensity of the  $N_2$  lines together with the increase of concentration of  $O_2$  in He (axial view). With a percentage of 1.5%  $O_2$  in He, the  $N_2$  lines dropped over four times.



Fig. 9. Plasma jet emission spectra in the 300–460-nm range, for several  $O_2$  admixtures in He: (a) 0%, (b) 0.5%, and (c) 1.5%. He flow rate: 2.5 L/min. High-voltage amplitude: 25 kV. Pulse repetition frequency: 100 pps. Spectrometer integration time: 100 ms. Axial view.

As far as the 777 nm line of atomic oxygen is concerned, it has a continuous increase up to a concentration of  $1.5\% O_2$  in He (Fig. 7). We suppose that the O I 777 nm line intensity

1000

800

600

400

200

0 └─ 550

ntensity (arbitrary units)

He I: 587.6 nm

O I: 614.6 nm

600



Wavelength (nm)

650

ШШ

 $H_{
m cc}$  I: 656

645.6 nm

0

ШШ

ø

667.

He I: (

705 nm

Heli

715.7 nm

0

700

700.2 nm

Ш

777

... 0

750

800



Fig. 11. Dependence of the O I 777 nm line intensity of the O<sub>2</sub> admixtures in He, in the case of axial observation of the emission spectra. He flow rate: 2.5 L/min. High-voltage amplitude: 25 kV. Pulse repetition frequency: 100 pps. Spectrometer integration time: 100 ms.

is related to atomic oxygen concentration. When the value of  $O_2$  in He is over 1.5%, the decrease of the plasma jet current becomes sufficiently important to lead to a decrease of the amplitude of the O I 777 nm line. The interaction between electrons and oxygen molecules also intensifies with high  $O_2$  concentrations. This is demonstrated by the occurrence, at 2%  $O_2$ , of new spectral lines of atomic oxygen: 614.6, 645.6, 700.2, and 715.7 nm (Fig. 10).

The same evolution of the O I 777 nm line intensity occurs in the case of axial observation of the emission spectra (Fig. 11). In this case, note that the intensity of the spectral lines is a lot higher compared to that with the side view (the integration time of the spectrometer is only 100 ms, while that with the side view is 600 ms). The explanation is that, with axial observation, the luminous spot (Fig. 4) covers a larger part of the area seen by the lens transmitting the luminous information to the spectrometer.

The presented experiments demonstrate that the optimal value of the concentration of  $O_2$  in He is 1.5%. The obtained value is three times higher than that in the case of experiments in [37] and [39] and of theoretical simulation in [38].

Accordingly, the quantity of atomic oxygen in the plasma jet increases, and the plasma jet becomes more chemically active. The explanation for this increase of chemical activity is that there are three high-voltage electrodes in the discharge room of the new device, which are placed in such a manner that three independent discharges take place. Each discharge has an optimal percentage of 0.5% O<sub>2</sub> in He that maximizes the quantity of atomic oxygen in the plasma. The plasmas of the three discharges unite in a single jet, which contains a quantity of atomic oxygen that is a lot higher than that of the plasma of each discharge.

### **IV. CONCLUSION**

One method of increasing the chemical activity of the highvoltage pulsed cold atmospheric plasma jets is to form devices with more tubular high-voltage needle-type electrodes electrically connected in parallel. The chemical activation gas is introduced through these electrodes. The electrodes must be placed so that independent electrical discharges occur inside the discharge room. Uniting the plasmas of these discharges in a single jet multiplies the quantity of atomic oxygen in the plasma jet, which becomes more chemically active. The increase of the number of high-voltage electrodes and the appropriate multiplication of the chemical activity of the plasma jet constitute issues to be studied furthermore.

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